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PATENT & TRADEMARK OFFICEAPPLICANT
Vishnu K. Agarwal et alFILING DATE
January 15, 2002GROUP
2813

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
YK	AA 6,204,070	03/2001	Kim			
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	AC 6,391,803	05/2002	Kim et al			
YK	AD 6,420,230	07/2002	Derderian			
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	AI					
	AJ					
	AK					
	AL					

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
YK	AM KR 2002002157A	01/2002	Korea				
	AN						
	AO						
	AP						
	AQ						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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AS		
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1 of 1

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Vishnu K. AgarwalPriority FILING DATE
August 31, 2000Priority GROUP
281310/050334
05/15/02

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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<i>VK</i>	AR		A.W. Ott, et al., "Atomic Layer Controlled Deposition of Al ₂ O ₃ Films Using Binary Reaction Sequence Chemistry", Applied Surface Science (107), 1996, pps. 128-136.				
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YJ	AA	09/653,149		Derderian			08/31/00
YJ	AB	09/652,532		Derderian (as filed and amended 11/29/01)			08/31/00
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	AL						
	AM						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AN							
	AO							
	AP							
	AQ							

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